# Acoustic Characterization of a Photomask Cleaning System







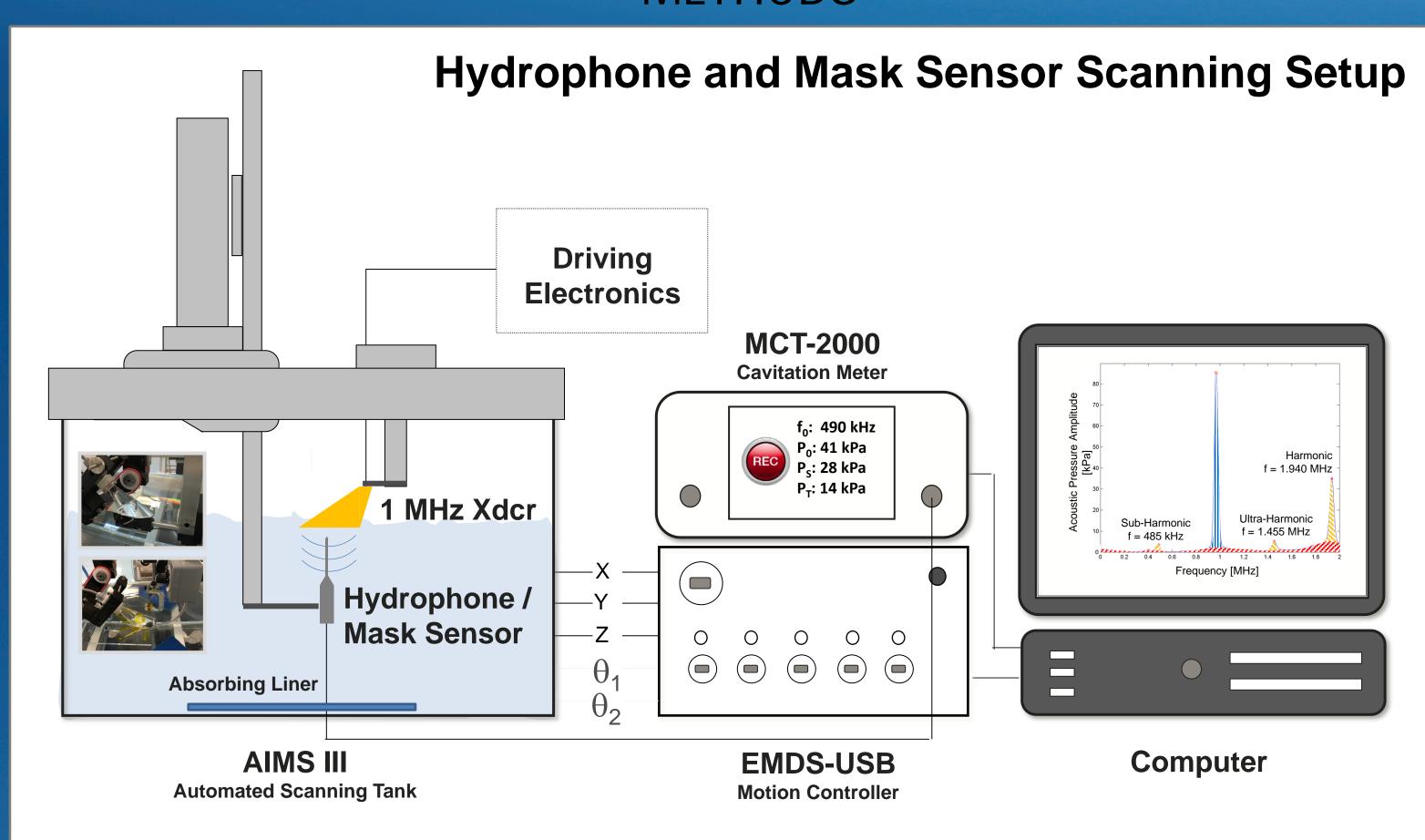
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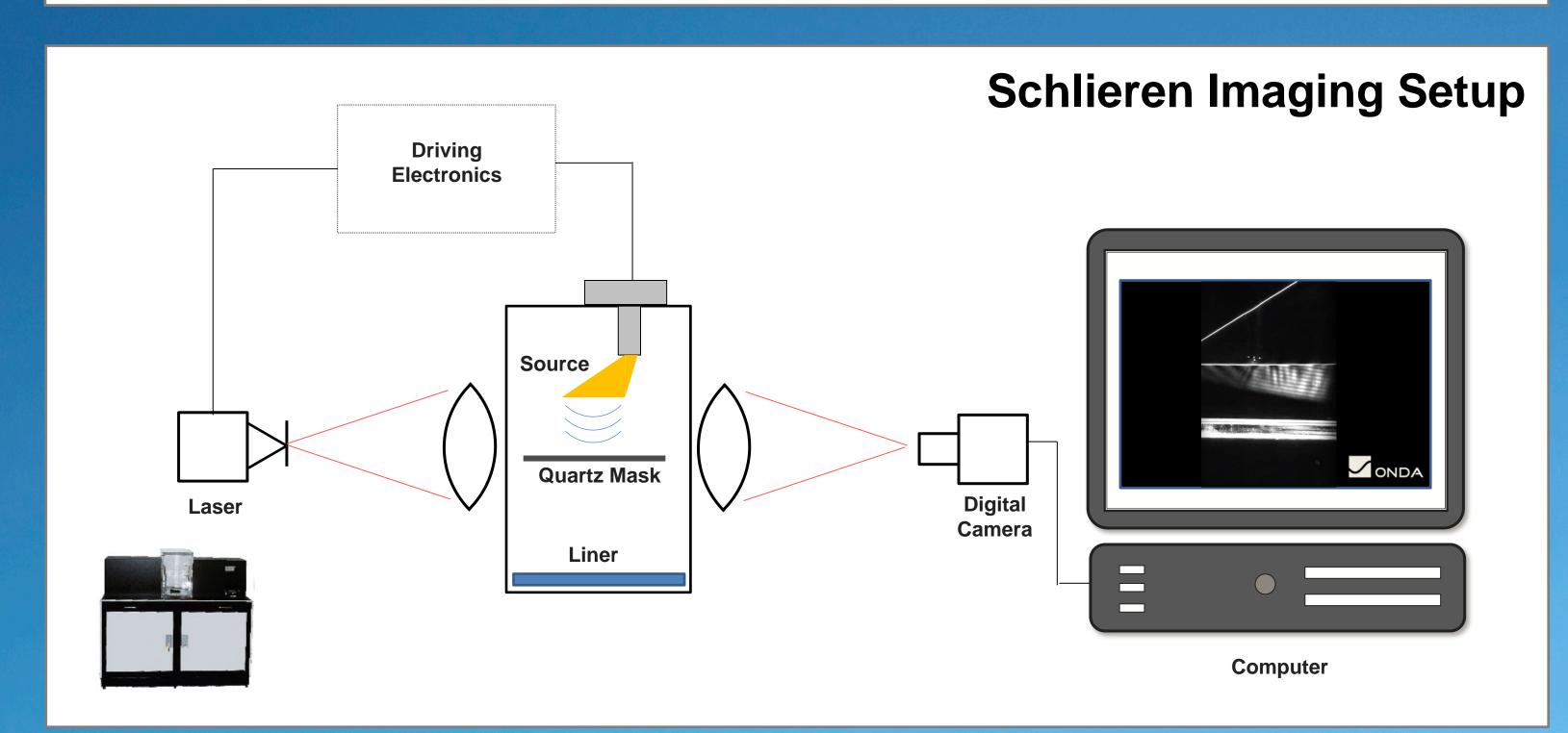
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## INTRODUCTION

Although megasonic technology is widely used to clean photomasks, the acoustic performance is not well understood. Of all the process parameters that influence cleaning (e.g., temperature, flow, pH, gas concentration, mechanical translation, etc.) the characterization of the ultrasonic field remains elusive. The shift to EUV lithography processes elevates this issue further since the risk of yield loss is even higher in the absence of a pellicle. This study aims to achieve a deeper understanding of the complex acoustic behavior by presenting results from three independent measurement techniques.

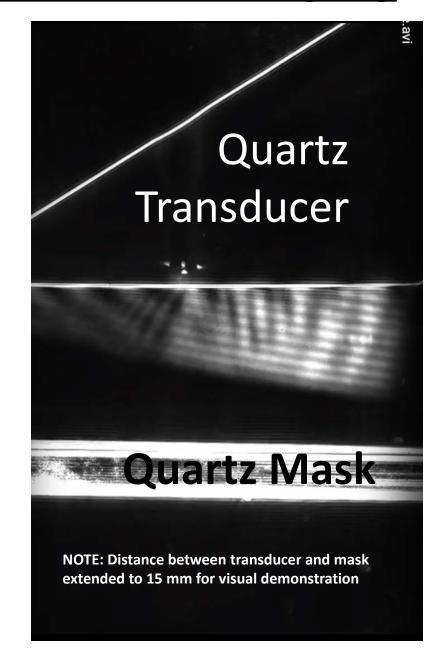
# METHODS



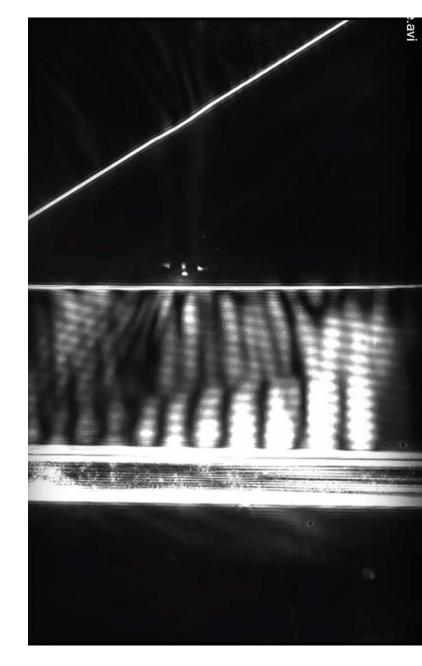


# **RESULTS & DISCUSSION**

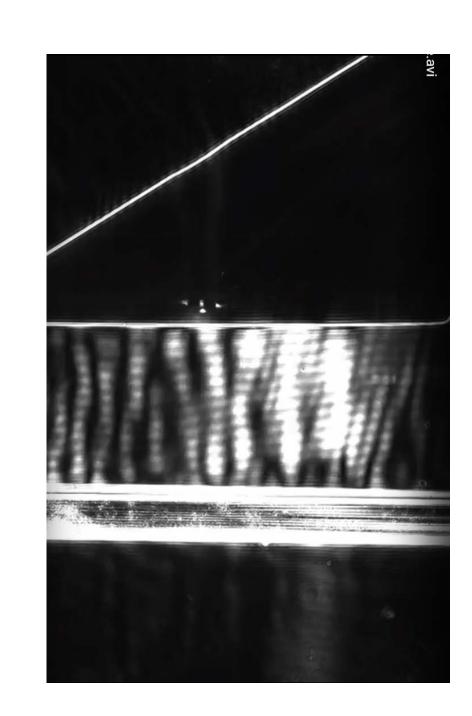
### **Schlieren Imaging**



Wave propagates at an offset angle from transducer

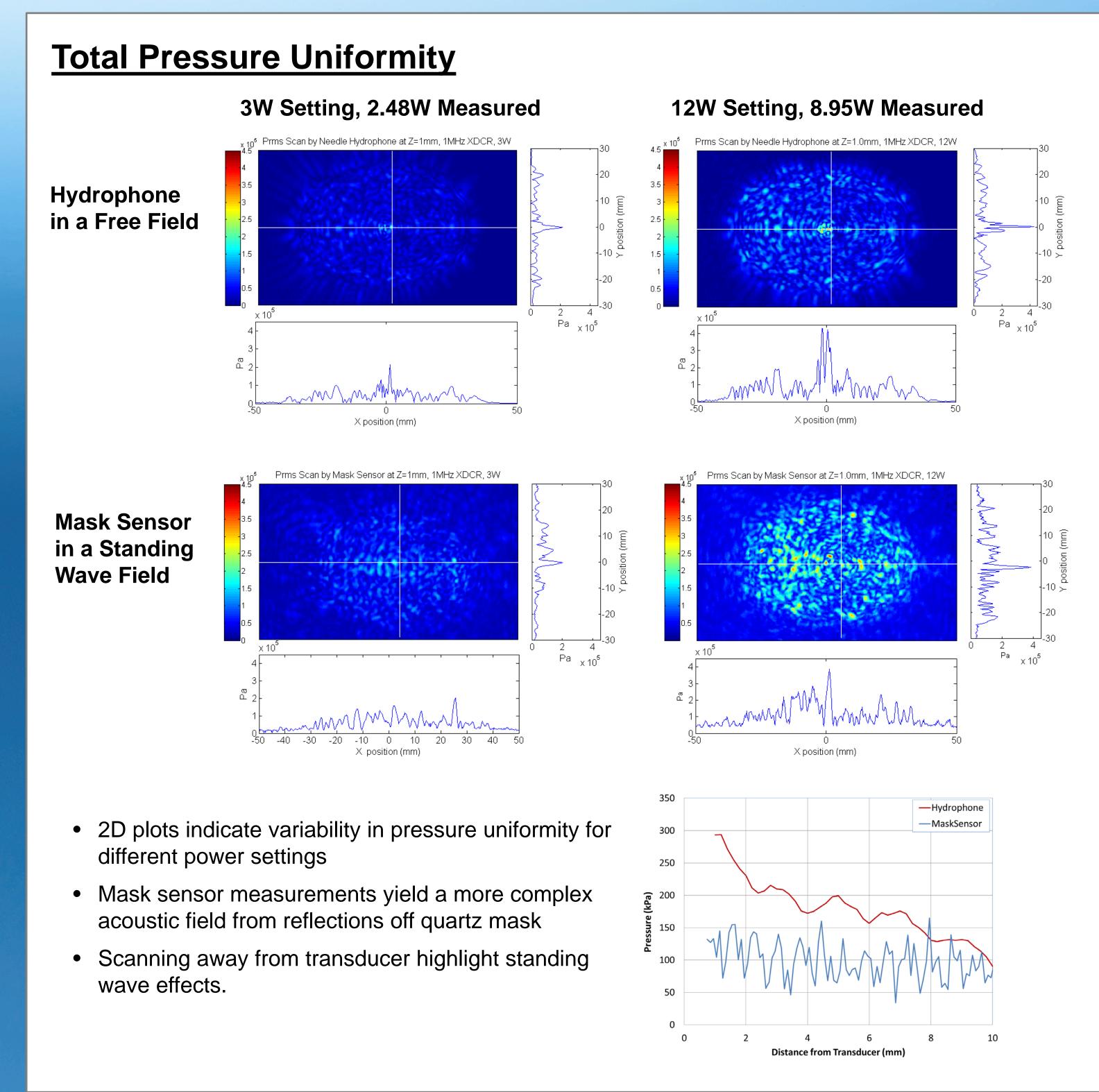


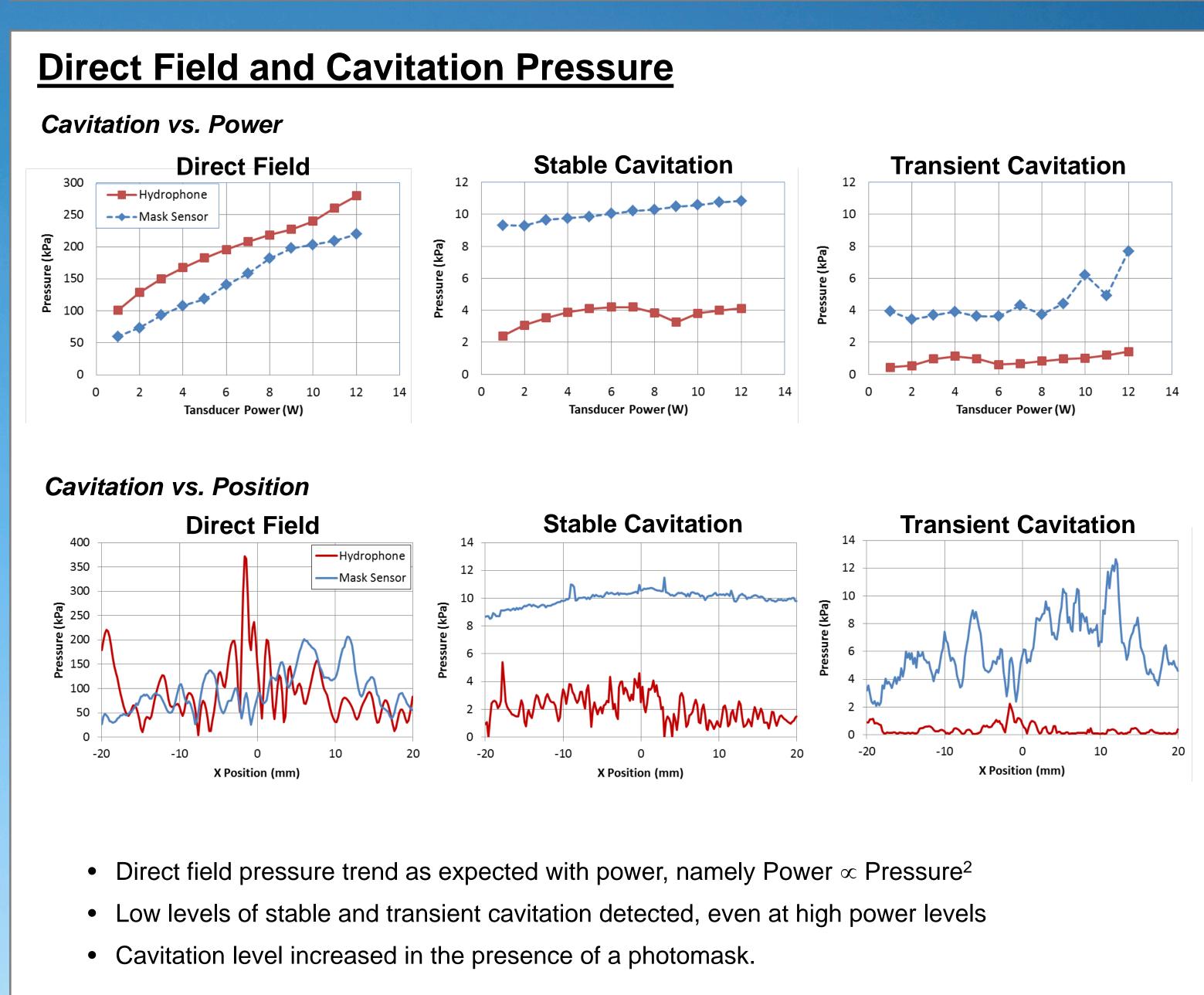
Incident wave disturbed by reflected wave from both top and bottom surface of quartz; some waves transmit through quartz mask



The resultant sound field reveal a complex pattern from multiple reflections

# RESULTS & DISCUSSION





### CONCLUSIONS

Through the use of different measurement techniques, a deeper understanding of the acoustic performance for a mask cleaning system has been achieved. This helps bridge the gap in connecting the ultrasound with cleaning performance.